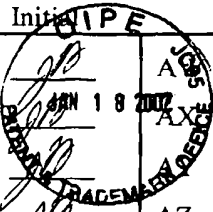





INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. 010819	Serial No. 09/891,511
	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit: 2812

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	Applicant(s): NAKASUJI, et al.	
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